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TECHNOLOGY CENTER 2800

In re Application of:

Pan et al.

Serial No.: 09/073,494

Filed: May 6, 1998

For: TECHNIQUE FOR ELIMINATION OF  
PITTING ON SILICON SUBSTRATE  
DURING GATE STACK ETCH

Examiner: H. Vu

Group Art Unit: 2811

Attorney Docket No.: 2915.1US (96-149.1)

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21/F  
FJONES

**PRELIMINARY AMENDMENT**

Box RCE

Hon. Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

Prior to examination of the claims on the merits in the above-identified application,  
please amend this application as follows:

**IN THE CLAIMS:**

Please note that all claims currently pending and under consideration in the referenced  
application are shown below, in clean form, for clarity. A marked up version of the claims with  
amendments is attached hereto.

TRASKBRITT, PC  
ATTY. REF. NO. 2915.1US(96-149.1)